

ASMEX.186DV1



#141EDS
5/20/03
PATENT
Suler

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Raaijmakers et al.

Group Art Unit 2812

App. No. : 09/764,711

Filed : January 18, 2001

For : METHOD OF DEPOSITING
SILICON WITH HIGH STEP
COVERAGE

Examiner : A. Roman

TECHNOLOGY CENTER 2800
MAY 15 2003

RECEIVED

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing one reference that is also enclosed. This Information Disclosure Statement is being filed before the mailing date of a final action under 37 C.F.R. § 1.113 and before the mailing date of a Notice of Allowance under § 1.311. A certification under 37 C.F.R. § 1.97(e) is set forth below. Thus, no fee is required as set forth in 37 C.F.R. § 1.97(c).

CERTIFICATION UNDER 37 C.F.R. § 1.97(e)(2)

I hereby certify that no item of information contained in this Statement was cited in a communication from a foreign Patent Office in a counterpart foreign application, or, to my knowledge after making reasonable inquiry, was known to any individual designated in 37 C.F.R. § 1.56(c) more than three months days/months prior to the filing of this Information

Appl. No. : 09/764,711
Filed : January 18, 2001

Disclosure Statement.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: May 8, 2003

By: Adeel S. Akhtar
Adeel S. Akhtar
Registration No. 41,394
Attorney of Record
Customer No. 20,995
(415) 954-4114

W:\DOCS\ZYW\ZYW-1694.DOC
050703